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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: NAKANO, et al.
Serial No.: 10/075,244
Filed: February 15, 2002
For: METHOD AND APPARATUS FOR PLASMA PROCESSING
Group: 1762
Examiner: Unassigned

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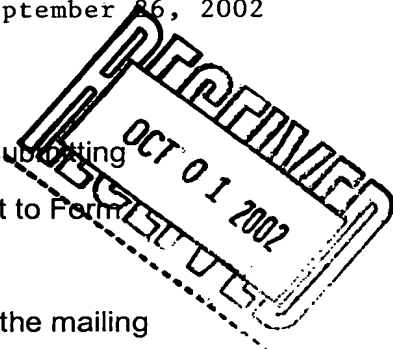
INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR 1.97 & 1.98

Assistant Commissioner for Patents
Washington, D.C. 20231

September 26, 2002

Sir:

In the matter of the above-identified application, applicants are submitting herewith a copy of the documents listed in the attached form equivalent to Form PTO-1449 for the Examiner's consideration.



This information disclosure statement is being submitted before the mailing date of a first office action on the merits.

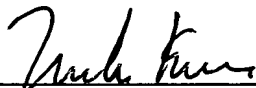
On information and belief, I hereby certify that each item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not than more than three months prior to the filing of this statement.

To the extent that, the documents listed on the attached form equivalent to Form PTO-1449, are not in the English language, the requirement of 37 CFR 1.98(a)(3) for a concise explanation of the relevance is satisfied by English language abstracts.

It is respectfully requested that this information disclosure statement be considered by the Examiner.

Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account No. 01-2135 (501.41175X00) and please credit any excess fees to such deposit account.

Respectfully submitted,



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MK/nbf
Attachments
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